

Date	Topic of lecture	Exercise (H=home; S=spot)	Teacher	Readings for this lecture
				<b>Introduction to Microfabrication</b>
27 Feb	Introduction		SF	Chapter 1
	Litho & etching		SF	Chapters 9,11
	Silicon		VO	Chapter 4
5 March	Cleaning & cleanroom & safety		VO	Chapters 12,35
	Lab device (sputtering)		SF	Chapter 5
		S1: Thin film, litho & etch	VO, SF	Chapters 12, 35
		<b>LAB REGISTRATION STARTS</b>		
12 March		H1: thin film, litho, etch	MA	
	Oxidation		VO	Chapter 13
	Thin films		SF	
		<b>FIRST GROUP IN LAB MARCH XX</b>		
19 March		H2: resistors, caps	LM	
	Doping (incl. Epi)		VO	Chapters 6,14,15
		S2: oxidation & doping	VO, SF	
26 March		H3: oxide, doping	LM	
	Bonding & CMP		VO	Chapters 16,17
	Integration	<b>LAST GROUP IN LAB XXX</b>	SF	Chapter 25
2 April	Easter holiday			
9 April		<b>H4: lab reports discussed</b>	MM	
	MEMS 1 (etch)		SF	Chapters 21,22
		S3: MEMS 1	SF	
16 April	<b>exam week, no teaching</b>			
23 April		H5: MEMS 1	MM	
	CMOS		VO	Chapter 26
		S4: CMOS starters	VO	
25 April Thursday		H6: CMOS	VO	
	MEMS 2 (bulk)		SF	Chapter 30
		S5: MEMS 2	SF	
30 April	Yield & reliability		VO	Chapter 36
	Nano-CMOS, metallization & Moore's law		VO	Chapters 28,38
		S6: metallization	VO	
7 May		H7: yield; economics	VO	
	MEMS 3 (surface)		SF	Chapter 29
		S7: MEMS 3	SF	
14 May		H8: MEMS 3	SF	
	Scaling		SF	Chapter 25, 38
	Economics of microfabrication		SF	
	Q&A session		VO, SF	
21 May	Exam	time: 9-12 o'clock	all	